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March 16, 2006

VIA FACSIMILE
EXPEDITED PROCEDURE

To: Examiner Michail Kornakov
Group Art Unit No. 1746
U. S. P. T. O.

Facsimile No. 571-273-8300

From: Phillip E. Miller

Facsimile No. 703-761-2375

Re: Filing of Statement of Substance of Interview
U. S. Patent Application Serial No. 09/935,699
Our Ref: NGB.172

Dear Examiner:

Enclosed please find a Statement of Substance of Interview which covers the Personal Interview that we conducted with you on February 24, 2006.

Thank you in advance for your kind consideration of this case.

Very truly yours,


Phillip E. Miller

PEM/rap
Enclosure

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Uemura et al.

Serial No.: 09/935,699

Group Art Unit: 1733

Filed: August 24, 2001

Examiner: Kornakov, Michail

For: METHOD FOR MANUFACTURING A GROUP III NITRIDE COMPOUND
SEMICONDUCTOR DEVICEHonorable Commissioner of Patents
Alexandria, VA 22313-1450RECEIVED
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STATEMENT OF SUBSTANCE OF INTERVIEW

Sir:

Applicant provides herewith his Statement of Substance of the telephone interview which was conducted between the Examiner and Applicant on February 24, 2006.

1. **Brief description of nature of exhibits/demonstrations:** N/A
2. **Claims discussed:** 21, 38.
3. **Prior art discussed:** Maniar
4. **Proposed amendments discussed:** The Examiner indicated that adding the limitations "*wherein said irradiating said surface of said wafer is performed after said patterning said resist layer*" or "*supplying said oxygen molecules to said surface of said wafer by supplying an oxygen-containing gas to said surface*" to claims 21 and 38 would likely overcome Maniar et al. (U. S. 5,525,542).
5. **Arguments made by Applicant's representative:** Applicant's representative pointed out, among other things, that Maniar does not teach or suggest "*wherein said irradiating said surface of said wafer is performed after said patterning said resist layer*", as recited in claim 32.
6. **Other pertinent matters:** N/A
7. **Result of Interview:** No agreement was reached.

Date: 3/16/06

Respectfully Submitted,

Phillip E. Miller
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CERTIFICATE OF FACSIMILE TRANSMISSION

I hereby certify that the foregoing was filed by facsimile with the United States Patent and Trademark Office, Examiner Michael Kornokov, Group Art Unit # 1746 at fax number (571) 273-8300 this 16th day of March, 2006.



Phillip E. Miller
Reg. No. 46,060